Model 1020 Plasma Cleaner Specifications

| Plasma system | High frequency (13.56 MHz) oscillating field system coupled to a quartz and stainless steel plasma chamber
|               | Ion energies less than 12 eV
|               | Compatible with TEM specimen holders for transmission electron microscopes manufactured by:
|               | • FEI Company/Philips Electron Optics
|               | • Hitachi High Technologies America Inc.
|               | • JEOL Ltd.
|               | • Carl Zeiss Microscopy/LEO Electron Microscopes
|               | • Topcon Corp.
| Vacuum system | Oil-free turbomolecular drag pump and a multistage diaphragm pump
|               | Ultimate vacuum of $1 \times 10^{-7}$ mbar
| Gas           | 25% oxygen and 75% argon
|               | Nominal 10 psi (200 kPa) delivery pressure
|               | Flow rate is factory set and can be adjusted via a potentiometer located on the service panel
| Dimensions    | 23.2 in (59 cm) width x 20.4 in (52 cm) height x 23.2 in (59 cm) depth
| Weight        | 133.5 lb (60.6 kg)
### Model 1020 Plasma Cleaner Specifications

| User interface | Single control panel to initiate vacuum, plasma, and timer  
|                | Process timer for automatic termination  
|                | Service panel is easily accessible |
| Power requirements | 100/120/220/240 V AC, 50/60 Hz, 660 W |
| Warranty | Two years |